Information & Control NA TC Chapter

Meeting Summary and Minutes

NA Summer Meetings
9:00-12:00, 1:00-4:00 PM Pacific
Wednesday, June 4, 2025
Milpitas, CA

TC Chapter Announcements

Next TC Chapter Meeting

SEMICON West

Wednesday, October 8, 2025

9:00-12:00, 1:00-4:00 PM Mountain Time

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: Co-Chairs: James Moyne (Applied Materials / University of Michigan), Brian Rubow (Cimetrix), Albert Fuchigami (PEER Group)
SEMI Staff: Michelle Sun

Company	*Last*	*First*	*Company*	*Last*	*First*
Agileo Automation	*Golra*	*Fahad*	Jeanne Cickay	*Cickay*	*Jeanne*
Applied Materials, Inc.	*Perevoztchikov*	*Konstantin*	Micron Technology, Inc.	*Cicero*	*Jason*
Applied Materials, Inc.	*Moyne*	*James*	NAURA	*Cao*	*Clark*
Cimetrix	*Weber*	*Alan*	Onto Innovation	*Benda*	*Stanislav*
Cimetrix Incorporated	*Rubow*	*Brian*	Onto Innovation	*McLane*	*Adam*
Cimetrix	*Tracey*	*Tami*	PEER Group Inc.	Fuchigami	Albert
Eunodata Co., Ltd.	*KY*	*Kun-Yung*	SCREEN Semiconductor Solutions Co., Ltd.	Nishimura	Takayuki
Hitachi High-Tech Corporation	*Toyoshima*	*Yuko*	SEMI	Sun	Michelle
Intel Corp.	*Bond*	*Ryan*	Self	*Howard*	*Richard*
Intel Corporation	*Maloney*	*Chris*			

Table 2 Leadership Changes

WG/TF/SC/TC Name	*Previous Leader*	*New Leader*
CDS TF		Alan Weber (Cimetrix)
EDP TF		Alan Weber (Cimetrix)

Table 3 TC Chapter Structure Changes

Previous WG/TF/SC Name	*New WG/TF/SC Name or Status Change*
None	

Table 4 Ballot Results

Document #	*Document Title*	*Committee Action*
7178	Revision to SEMI E164-0414 (Reapproved 0721), Specification for EDA Common Metadata	**Failed**
7270	Line Item Revision to SEMI E151-1211 (Reapproved 0517), Guide for Understanding Data Quality	
LI-1	Changes to address references that are no longer valid or no longer needed	**Passed**
7311A	Line Item Revision to SEMI E191-1024 - Specification for Computing Device Cybersecurity Status Reporting and SEMI E191.1-1024 - Specification for SECS-II Protocol for Computing Device Cybersecurity Status Reporting	
LI-1	Add additional requirements and clarifications to cybersecurity status information to be reported	**Passed**
LI-2	Address issues raised by TF members	**Passed**
7321A	Line Item Revision to SEMI E120-0922 (Reapproved 0823) Specification for the Common Equipment Model (CEM), SEMI E120.2-0823 Specification for Protocol Buffers for Common Equipment Model (CEM), SEMI E125-0923 Specification for Equipment Self Description (EqSD), SEMI E125.2-0923 Specification for Protocol Buffers for Equipment Self Description (EqSD), SEMI E132-0624 Specification for Equipment Client Authentication and Authorization, SEMI E132.2-0624 Specification for Protocol Buffers for Equipment Client Authentication And Authorization (ECA), SEMI E134-0624 Specification for Data Collection Management, SEMI E134.2-0624 Specification for Protocol Buffers of Data Collection Management, and SEMI E179-0624 Specification for Protocol Buffers Common Components	
LI-1	Add filtering capabilities to retrieving SEMI E125 metadata	**Failed**
LI-2	Update issues raised by TF members	**Failed**
7347	Reapproval of SEMI E54.18-0914 (Reapproved 0420) - Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pump Device	**Passed**
7348	Reapproval of SEMI E54.23-0520 - Specification for Sensor/Actuator Network Communications for CC-LINK® IE	**Failed**

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Ratification Ballot Results

Document #	*Document Title*	*ISC A&R Action*	*A&R Forms*
R7240	Revision to SEMI E157-0324, Specification for Module Process Tracking, with title change to: Specification for Module and Substrate Process Tracking	**Passed**	

Note 1: **Passed** Ratification ballots will be submitted to SEMI publication for final processing.

Note 2: **Failed** Ratification ballots were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 6 Activities Approved by the GCS between meetings of the TC Chapter

#	*Type*	*SC/TF/WG*	*Details*
7357	SNARF Approval	PCS	New Standard: Specification for Failure Analysis Reporting
7381	SNARF Approval	ABFI	Revision to Add a New Subordinate Standard: Specification for Transforming Non-E142 XY Coordinates to SEMI E142-0125: Specification for Substrate Mapping

Table 7 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	*Type*	*SC/TF/WG*	*Details*
7376	SNARF	GEM300	Line Item Revision to SEMI E30-0125 - Specification for the Generic Model for Communications and Control of Manufacturing Equipment (GEM), SEMI E30.1-0217 (Reapproved 0423) Specification for Inspection and Review Specific Equipment Model (ISEM)
7377	SNARF	GEM300	Line Item Revision to SEMI E40-0324 - Specification for Processing Management and SEMI E40.1-1218 (0324) Specification for SECS-II Protocol for Processing Management
7378	SNARF	GEM300	Line Item Revision to SEMI E87-0225 - Specification for Carrier Management (CMS) and SEMI E87.1-0225 - Specification for SECS-II Protocol for Carrier Management (CMS)
7379	SNARF	GEM300	Line Item Revision to SEMI E90-0624 - Specification for Substrate Tracking and SEMI E90.1-0624 - Specification for SECS-II Protocol Substrate Tracking
7380	SNARF	ABFI	Line Item Revision to SEMI E142-0225 - Specification for Substrate Mapping, SEMI E142.1-0225 — Specification for XML Schema for Substrate Mapping, SEMI E142.2-1016 (0225) — Specification for SECS II Protocol for Substrate Mapping, SEMI E142.3-1016 (0225) — Specification for Web Services for Substrate Mapping, SEMI E142.4-1022 (0225) — Specification for SECS II Protocol for Substrate Mapping Using Item Transfer

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:
http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF

Table 8 Authorized Ballots

#	*When*	*TF*	*Details*
6743C	Cycle 6, 7-2025	GUI	Revision to SEMI E95-1101, Specification for Human Interface for Semiconductor Manufacturing Equipment
6926A	Cycle 6, 7-2025	CDS	New Standard: Specification for Equipment Operator Access Management and Monitoring
7178A	Cycle 6, 7-2025	DDA	Revision to SEMI E164-0414 (Reapproved 0721), Specification for EDA Common Metadata

Table 8 Authorized Ballots

#	When	TF	Details
7321B	Cycle 6, 7-2025	DDA	Line Item Revision to SEMI E120-0922 (Reapproved 1224) Specification for the Common Equipment Model (CEM), SEMI E120.2-1224 Specification for Protocol Buffers for Common Equipment Model (CEM), SEMI E125-1224, Specification for Equipment Self Description (EqSD), SEMI E125.2-1224, Specification for Protocol Buffers for Equipment Self Description (EqSD), SEMI E132-0624, Specification for Equipment Client Authentication and Authorization, SEMI E132.2-1224, Specification for Protocol Buffers for Equipment Client Authentication And Authorization (ECA), SEMI E134-1224, Specification for Data Collection Management, SEMI E134.2-1224, Specification for Protocol Buffers of Data Collection Management, and SEMI E179-1224, Specification for Protocol Buffers Common Components
7344	Cycle 6, 7-2025	ABFI	Line Item Revision to SEMI E192-0121 – Guide for Equipment Adoption Criteria for GEM and GEM-Related Standards
7345	Cycle 6, 7-2025	GEM300	Line Item Revision to SEMI E90-0624 - Specification for Substrate Tracking and SEMI E90.1-0624 - Specification for SECS-II Protocol Substrate Tracking
7346	Cycle 6, 7-2025	Sensor Bus	Line Item Revision to SEMI E54.23-0520, Specification for Sensor/Actuator Network Communications for CC-Link®IE
7355	Cycle 6, 7-2025	Sensor Bus	Reapproval of SEMI E54.22-0914 - Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pressure Gauges
7376	Cycle 6, 7-2025	GEM300	Line Item Revision to SEMI E30-0125 - Specification for the Generic Model for Communications and Control of Manufacturing Equipment (GEM), SEMI E30-0125, SEMI E30.1-0217 (Reapproved 0423) Specification for Inspection and Review Specific Equipment Model (ISEM)
7377	Cycle 6, 7-2025	GEM300	Line Item Revision to SEMI E40-0324 - Specification for Processing Management and SEMI E40.1-1218 (0324) Specification for SECS-II Protocol for Processing Management
7378	Cycle 6, 7-2025	GEM300	Line Item Revision to SEMI E87-0225 - Specification for Carrier Management (CMS) and SEMI E87.1-0225 - Specification for SECS-II Protocol for Carrier Management (CMS)
7379	Cycle 6, 7-2025	GEM300	Line Item Revision to SEMI E90-0624 - Specification for Substrate Tracking and SEMI E90.1-0624 - Specification for SECS-II Protocol Substrate Tracking
7380	Cycle 6, 7-2025	ABFI	Line Item Revision to SEMI E142-0225 - Specification for Substrate Mapping, SEMI E142.1-0225 — Specification for XML Schema for Substrate Mapping, SEMI E142.2-1016 (0225) — Specification for SECS II Protocol for Substrate Mapping, SEMI E142.3-1016 (0225) — Specification for Web Services for Substrate Mapping, SEMI E142.4-1022 (0225) — Specification for SECS II Protocol for Substrate Mapping Using Item Transfer
7381	Cycle 6, 7-2025	ABFI	Revision to Add a New Subordinate Standard: Specification for Transforming Non-E142 XY Coordinates to SEMI E142-0125: Specification for Substrate Mapping
7382	Cycle 6, 7-2025	ESEC	Reapproval of SEMI E175-1116 - Specification for Subsystem Energy Saving Mode Communication (SESMC)

Table 9 SNARF(s) Granted a One-Year Extension

#	TF	Title	Expiration Date
6926	CDS	New Standard: Specification for Equipment Operator Access Management and Monitoring	6/4/2026

Table 10 SNARF(s) Cancelled

#	*TF*	*Title*
7064	GEM300	Reapproval of SEMI E40-1218, Specification for Processing Management
7276	GEM300	Line Item Revision to SEMI E30-0224 - Specification for the Generic Model for Communications and Control of Manufacturing Equipment (GEM)
7278	GEM300	Line Item Revision to SEMI E90-0624, Specification for Substrate Tracking and SEMI E90.1-0624, Specification for SECS-II Protocol Substrate Tracking

Table 11 Standard(s) to receive Inactive Status

Standard Designation	*Title*
SEMI E54.17	Specification of Sensor/Actuator Network for A-LINK
SEMI E54.19	Specification for Sensor/Actuator Network for MECHATROLINK
SEMI E54.21	Specification for Sensor Actuator Network for Motionnet Communication

Table 12 New Action Items

Item #	*Assigned to*	*Details*
1	Michelle Sun (SEMI)	Obtain LOA for Sensor Bus E54.18 - **WIP**
2	Michelle Sun (SEMI)	Ask Publications to make these Standards go Inactive: E54.17, E54.19, E54.21 – **DONE**
3	Michelle Sun (SEMI)	Remove 7241 - **DONE**
4	Michelle Sun (SEMI)	Answer inquiry: Which building will the SEMI Standards Meetings be held, and which building(s) will the "Show/Exhibits" be in?
5	Michelle Sun (SEMI)	Ask Andreas if ESEC TF meeting can start at 10:00 instead of 9:30 - **DONE**

Table 13 Previous Meeting Action Items

Item #	*Assigned to*	*Details*
None		

1 Welcome, Reminders, and Introductions

Albert Fuchigami (PEER Group) called the meeting to order at 9:02. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: Required Meeting Elements March 2024

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion:	Approve the minutes as written
By / 2nd:	By: Brian Rubow / Cimetrix Incorporated Second: Takayuki Nishimura / SCREEN
Discussion:	None
Vote:	9-Y 0-N

Attachment: IC-Minutes-Feb-2025

3 Liaison Reports

3.1 *I&C Japan TC Chapter*

Takayuki Nishimura (SCREEN) reported for the I&C Japan TC Chapter. Of note:

- Meeting Schedule
    - Last meeting: April 18, 2025
    - Next meeting: October 21, 2025
- Authorized Ballots
    - 7354, Line Item Revision to SEMI E170-0520: SPECIFICATION FOR SECURED FOUNDATION OF RECIPE MANAGEMENT SYSTTEM (SFORMS) and SEMI E170.1-0520: SPECIFICATION FOR SECS-II PROTOCOL FOR SECURED FOUNDATION OF RECIPE MANAGEMENT SYSTEM
    - 7330, Line Item Revision to SEMI E174-0819 SPECIFICATION FOR WAFER JOB MANAGEMENT (WJM)

Attachment: JA_I&C_Liaison_2025_May_Ver1

3.2 *I&C Taiwan TC Chapter*

Michelle Sun (SEMI) reported for the I&C Taiwan TC Chapter. Of note:

- Meeting Schedule
    - Last meeting: November 29, 2024
    - Next meeting: June 12, 2025
- Authorized Activities
    - SNARF 7317, Major Revision of E187 - Specification for Cybersecurity of Fab Equipment

Attachment: IC Taiwan Liaison Report_20250417_V1

3.3 *I&C China TC Chapter*

Michelle Sun (SEMI) reported for the I&C China TC Chapter. Of note:

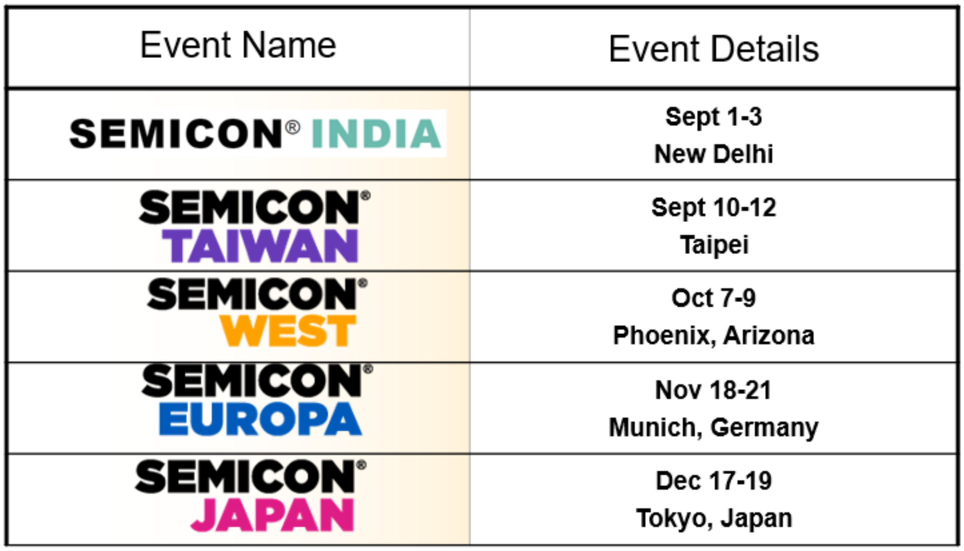
- Meeting Schedule
    - Last meeting: April 8, 2025
    - Next meeting: TBD
- Ballot Results
    - 7139, Line Item Revisions to E40-1218, Standard For Processing Management and E40.1-1218, Specification For SECS-II Protocol For Processing Management, **Passed with Technical Change**
    - 7140, Line Item Revisions to E94-0819R, Specification For Control Job Management and E94.1-0819R, Specification For SECS-II Protocol For Control Job Management (CJM), **Passed with Technical Change**

Attachment: China I&C Committee Chapter Liaison Report - April 2025 v1

3.4 *SEMI Staff Report*

Michelle Sun (SEMI) gave the SEMI Staff Report. Of note:

2025 Calendar of Events



Event Name	Event Details
SEMICON® INDIA	**Sept 1-3** **New Delhi**
SEMICON® TAIWAN	**Sept 10-12** **Taipei**
SEMICON® WEST	**Oct 7-9** **Phoenix, Arizona**
SEMICON® EUROPA	**Nov 18-21** **Munich, Germany**
SEMICON® JAPAN	**Dec 17-19** **Tokyo, Japan**

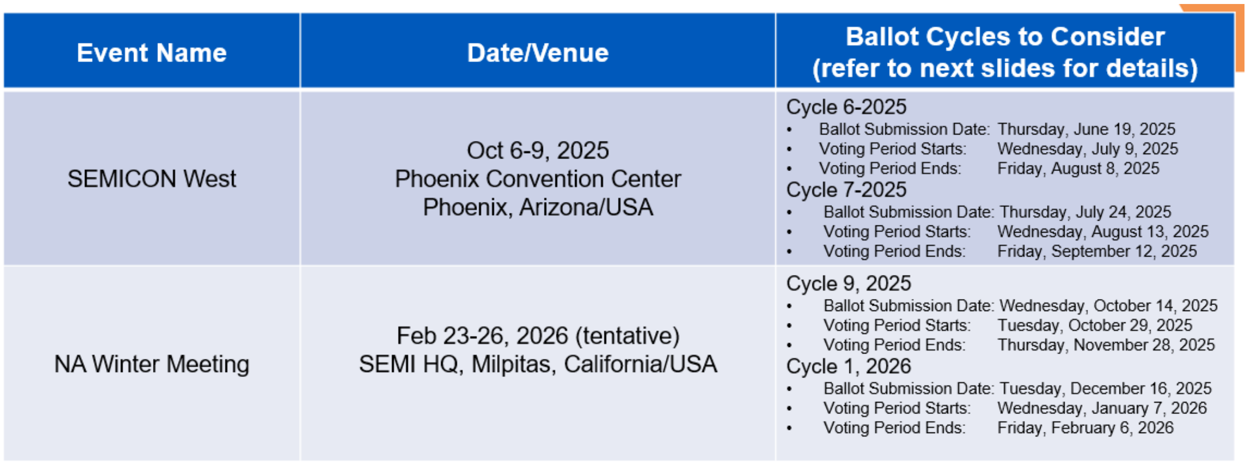
SEMICON West

- **2025—October 7-9 | Phoenix Convention Center | Phoenix, AZ**
- 2026—October 13-15 | Moscone Center | San Francisco, CA
- **2027—October 12-14 | Phoenix Convention Center | Phoenix, AZ**
- 2028—October 10-12 | Moscone Center | San Francisco, CA
- **2029—October 9-11 | Phoenix Convention Center | Phoenix, AZ**
- 2030—October 29-31 | Moscone Center | San Francisco, CA

SEMICON West 2025

- **Phoenix Convention Center**
    - 100 North Third Street, PHOENIX, AZ 85004
- **Standards meetings location**
    - North Hall
    - 2nd level

Upcoming NA Meetings 2025 & 2026



Event Name	Date/Venue	Ballot Cycles to Consider (refer to next slides for details)
SEMICON West	Oct 6-9, 2025 Phoenix Convention Center Phoenix, Arizona/USA	Cycle 6-2025 • Ballot Submission Date: Thursday, June 19, 2025 • Voting Period Starts: Wednesday, July 9, 2025 • Voting Period Ends: Friday, August 8, 2025 Cycle 7-2025 • Ballot Submission Date: Thursday, July 24, 2025 • Voting Period Starts: Wednesday, August 13, 2025 • Voting Period Ends: Friday, September 12, 2025
NA Winter Meeting	Feb 23-26, 2026 (tentative) SEMI HQ, Milpitas, California/USA	Cycle 9, 2025 • Ballot Submission Date: Wednesday, October 14, 2025 • Voting Period Starts: Tuesday, October 29, 2025 • Voting Period Ends: Thursday, November 28, 2025 Cycle 1, 2026 • Ballot Submission Date: Tuesday, December 16, 2025 • Voting Period Starts: Wednesday, January 7, 2026 • Voting Period Ends: Friday, February 6, 2026

Critical Dates for SEMI Standards Ballots

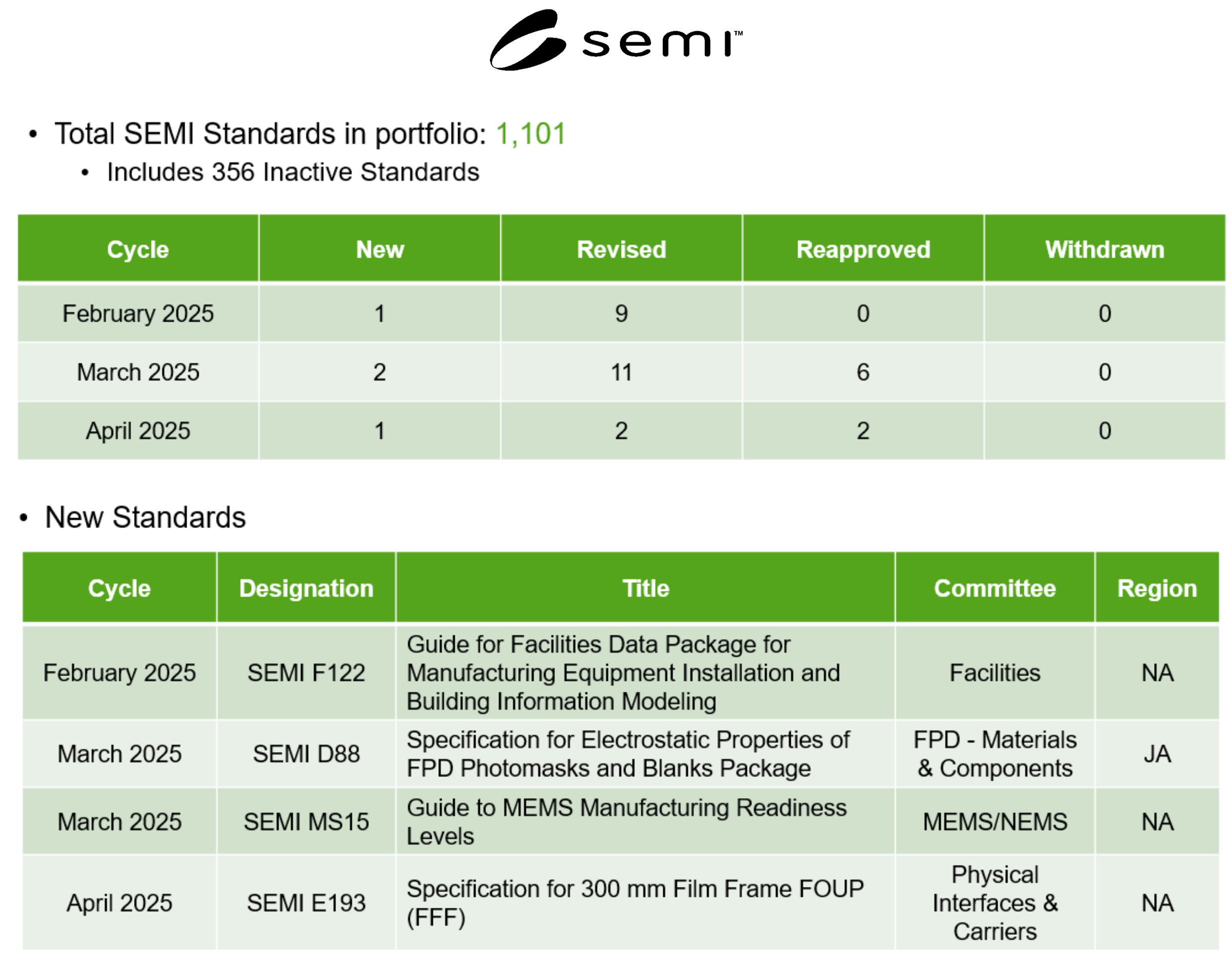
2025	Ballot Submission Deadline	Voting Opens	Voting Closes
Cycle 5	May 8	May 28	June 27
Cycle 6	June 19	July 9	August 8
Cycle 7	July 24	August 13	September 12
Cycle 8	September 3	September 24	October 24
Cycle 9 (Current)	~~October 1~~	~~October 21~~	~~November 20~~
Cycle 9 (Revised)	October 14	October 29	November 28

Critical Dates for SEMI Standards Ballots 2026 (Tentative)

Critical Dates for SEMI Standards Ballots 2026 *(Tentative)*

2026	Ballot Submission Deadline	Voting Opens	Voting Closes
Cycle 1	December 16, 2025	January 7	February 6
Cycle 2	January 23	February 11	March 13
Cycle 3	March 5	March 18	April 17
Cycle 4	March 30	April 14	May 14
Cycle 5	May 8	May 27	June 26
…	…	…	…

SEMI Standards Publications


- Total SEMI Standards in portfolio: 1,101
  - Includes 356 Inactive Standards

Cycle	New	Revised	Reapproved	Withdrawn
February 2025	1	9	0	0
March 2025	2	11	6	0
April 2025	1	2	2	0

- New Standards

Cycle	Designation	Title	Committee	Region
February 2025	SEMI F122	Guide for Facilities Data Package for Manufacturing Equipment Installation and Building Information Modeling	Facilities	NA
March 2025	SEMI D88	Specification for Electrostatic Properties of FPD Photomasks and Blanks Package	FPD - Materials & Components	JA
March 2025	SEMI MS15	Guide to MEMS Manufacturing Readiness Levels	MEMS/NEMS	NA
April 2025	SEMI E193	Specification for 300 mm Film Frame FOUP (FFF)	Physical Interfaces & Carriers	NA

Style Manual/Formatting Reminders

- Style Manual
  - Revision 10 (draft proposal) being reviewed with the Regs SC.
  - Mid-End June estimated publishing timeframe.
- Formatting Reminders
  - Referenced Standards and Documents section: Refer to Procedure Manual A3-5 for content requirements.
  - Terminology section: Refer to Procedure Manual A3-6 through A3-9 for content requirements.
- Regulations (Feb 20, 2024)
  - https://www.semi.org/sites/semi.org/files/2024-02/Standards%20Regulations%20February%2020%202024.pdf
- Procedure Manual (Sept 27, 2025)
  - https://www.semi.org/sites/semi.org/files/2024-09/Procedure%20Manual%20September%2027%2C%202024.pdf

Attachment: Staff Report June 2025 v4

4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

Document #7321, Line Item Revision to

SEMI E120-0922 (Reapproved 0823) Specification for the Common Equipment Model (CEM), SEMI E120.2-0823 Specification for Protocol Buffers for Common Equipment Model (CEM), SEMI E125-0923

Specification for Equipment Self Description (EqSD),

SEMI E125.2-0923 Specification for Protocol Buffers for Equipment Self Description (EqSD),

SEMI E132-0624 Specification for Equipment Client Authentication and Authorization,

SEMI E132.2-0624 Specification for Protocol Buffers for Equipment Client Authentication And Authorization (ECA),

SEMI E134-0624 Specification for Data Collection Management,

SEMI E134.2-0624 Specification for Protocol Buffers of Data Collection Management, and

SEMI E179-0624 Specification for Protocol Buffers Common Components

Motion:	Line item(s) [1], [2] failed TC Chapter review and will be returned to the TF for rework
By / 2nd:	By: Albert Fuchigami / PEER Group Inc. Second: Brian Rubow / Cimetrix Incorporated
Discussion:	None
Vote:	14-Y 0-N

4.1 Document #7178, Revision to SEMI E164-0414 (Reapproved 0721), Specification for EDA Common Metadata

Motion:	This Document failed TC Chapter review and will be returned to the TF for rework.
By / 2nd:	By: Albert Fuchigami / PEER Group Inc. Second: Alan Weber / Cimetrix
Discussion:	None
Vote:	13-Y 0-N

4.2 Document #7348, Reapproval of SEMI E54.23-0520 - Specification for Sensor/Actuator Network Communications for CC-LINK® IE

Motion:	This Document failed TC Chapter review and will be returned to the TF for rework.
By / 2nd:	By: Daniel Judd / Arlington Laboratory Second: James Moyne / Applied Materials, Inc.
Discussion:	None
Vote:	11-Y 0-N

5 Subcommittee and Task Force Reports

5.1 *CDS Task Force*

- Review of Comment for Ballot #7311A
- Discussion
    - Reviewed current, proposed, and future OS details for reporting
    - Update for Ballot #6926A set for next TF meeting
    - Requesting authorization to submit in Cycle 7 for:
    - Ballot #6926A - New Standard: Specification for Equipment Operator Access Management and Monitoring

Attachment: CDS TF Report 20250604 - 2

5.2 *DDA Task Force*

- EDA 'Core' Standards Update
  - Continue to propose ballot changes to address issues reported by TF Members as they implement the EDA Standards.
  - Discussed adding restrictions in SEMI E125 to prevent inconsistencies that would result in bad equipment models and clarify how metadata is handled differently from EDA Freeze 2.
- SEMI E164
  - Gained good feedback on first ballot attempt of the revised SEMI E164.
  - New SEMI E164 subordinate standard with SEMI E40 content is out as an informational ballot until June 20 to validate the subordinate standard approach.
  - Continue to develop JSONC files representing various content standard metadata as part of preparing suite of new SEMI E164 Subordinate Standards.

Attachment: DDA TF Report - June 2025_Rev 1.0

5.3 *EDP Task Force*

- Etch Component's Level 2 and Level 3 category definitions updated
  - Added some potential text for the Category Level Description (when not obvious)
- Next step for SEMI E190.1 Etch Components update:
  - Review & iterate the feedbacks through June 23rd, 2025
  - Finalization by June 23rd, 2025

Attachment: EDP TF Report - 20250602 v3

5.4 *GUI Task Force*

- Reviewed results of Informational Ballot (April 9 – May 9, 2025)
- Reviewed selected Comments on 6743C draft revision 3.4
- Took a vote on SNARF 6743 Extension
- Misunderstanding of Semicon West date in October
- SNARF 6743C does not expire until 11/8/2025

Attachment: GUI TF Report - 2025-06-03

5.5 *PCS Task Force*

Date and Event

- # of attendees in person: 8 (including staff)
- # of attendees remote/online: 4

TF Leadership & changes (if any): None

New SNARFs: None

Ballot Adjudication:

- 7270-1: Line Item update to SEMI E151-1211, Guide for understanding data quality
- Recommendation: [X] as balloted and will be forwarded to ISC A&R.

- Discussion negative moved to new business

Old Business

- ABFI TF and JSON header work liaison:
- Decided on PCS TF for failure analysis reporting. SNARF Approved by GCS
- SNARF approved in April. Hope to start JSON header work in 2-3 weeks.
- Sample holder SNARF also approved. TF under PIC to organize session to determine if two ballot efforts should be pursued jointly or separately.

Attachment: PCS-TF-report20250602

5.6 *GEM300 Task Force*

Ballot Adjudication

- R7240B-1 (E157)
    - Negative 1-1 Rainer Broleen (FABMation)
        - Use a mixture of SML and E5 notation for the data item format codes. Should use E5 notation consistently.
        - Discussion
        - StepCount format code is listed as 'U4' instead of '54' in multiple places. This should be fixed in a later revision.
    - Negative 2-1 Robert Flores
        - Requirement 108 does not seem clear; is the list size of the E157STATEMODEL variable constrained to being size 1 or 2, and if so wouldn't it be easier to just use an enumerated value? It say to report a list of size 0 if no E157 state models are supported but is that possible if supporting E157? And if not supporting E157, then no need to provide this status variable? Or is the length of the list equal to the number of E157 state model instances?
        - Discussion
        - If E157 is not supported, then no requirements in E157 are applicable. You could still provide the status variable as an empty list to clarify this.
        - The requirement says 'number of state models', not 'number of state model instances'.
    - Negative 2-2 Robert Flores
        - Requirements 113 and 114 seem to have the potential to conflict with each other. Requirement 113 says the substrate process tracking state shall be in EXECUTING when the substrate is being directly affected by recipe execution, but requirement 114 says that if initiated by an E40 ProcessJob the substrate process tracking state shall be EXECUTING if the ProcessJob is ACTIVE. What about the possibility of substrates moving between modules where there is no active recipe on the substrate but the ProcessJob is still active?
        - Discussion
        - This is not a change introduced in the 7240 ballot. The Module Process State Model has always included these requirements worded the same way. They are replicated in the new Substrate Process Tracking State Model.
        - For the Substrate Process Tracking State Model, the case presented is not applicable. The state model is focused on the substrate not the module. Requirement 114 could be clarified to express this.
        - For the Module Process State Model, the case presented is applicable. The module would be EXECUTING as stated.

SNARF Development

- Cancel 7276. It was replaced by 7312. - **Done**
- Cancel 7287. It is a duplicate of 7289. - **Done**
- Cancel 7064. Obsolete after well known ballot for E40 passed. - **Done**

Discussion

- Ballot 7345 – Batch Location states

Attachment: SEMI NA-ICC-GEM300-TF Meeting Summer 2025

5.7 *ABFI Task Force*

- Reviewed ballot 7344, which is ready for task force distribution.
- Reviewed E142 SNARF
- Another SNARF is planned for E142 regarding XY coordinates but is not yet ready.

Attachment: NA-ICC-ABFI-TF Report Summer 2025

6 Next Meeting and Adjournment

The next meeting is scheduled for Wednesday, October 8, 2025, at SEMICON West. See http://www.semi.org/standards-events for the current list of events.

Adjournment: 2:42.

Respectfully submitted by:

Michelle Sun
Coordinator
SEMI North America
Phone: 408.943.7982
Email: msun@semi.org

Minutes tentatively approved by:

James Moyne (UMich/AMAT), Co-chair	9/2/2025

Table 14 Index of Available Attachments[#1]

Title	*Title*
Required Meeting Elements March 2024	China I&C Committee Chapter Liaison Report - April 2025 v1
IC-Minutes-Feb-2025	Staff Report June 2025 v4
JA_I&C_Liaison_2025_May_Ver1	CDS TF Report 20250604 - 2
IC Taiwan Liaison Report_20250417_V1	DDA TF Report - June 2025_Rev 1.0
EDP TF Report - 20250602 v3	GUI TF Report - 2025-06-03
PCS-TF-report20250602	SEMI NA-ICC-GEM300-TF Meeting Summer 2025
NA-ICC-ABFI-TF Report Summer 2025	
AR - 7234	AR – 7270
AR – 7311A	AR - 7347

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.